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Contents

v *Conference Committee*

OPTOELECTRONICS TESTING AND MEASUREMENT

- 13498 02 **Anti-vibration surface reconstruction method for on-machine coherence scanning interferometric measurement** [13498-1]
- 13498 03 **Mathematical model of random sphere absolute measurement and the theory of multiple spheres random** [13498-2]
- 13498 04 **Tapped delay line time-to-digital converters calibration based on Geiger-mode avalanche photodiode** [13498-5]
- 13498 05 **A way to measure the target contrast in low light level based on image intensifier technology** [13498-6]
- 13498 06 **Recognition and suppression of phase-sensitive OTDR interference fading based on machine learning** [13498-7]
- 13498 07 **Research on automated test system for performance parameters of InGaAs PIN focal plane detectors** [13498-9]
- 13498 08 **Research on a method for repairing breakpoints in temperature data of colorimetric thermometers** [13498-10]
- 13498 09 **3D digital image correlation deformation measurements by a single color camera** [13498-11]
- 13498 0A **Research on calibration method of 222nm UV radiometer** [13498-12]
- 13498 0B **Research on spectral retro-reflection standard measurement and calibration device** [13498-14]
- 13498 0C **Research on calibration method for optical characteristics of pedestrian targets in autonomous vehicle testing** [13498-15]
- 13498 0D **Testing technique for tuning characteristics of scanning DBR lasers** [13498-17]

- 13498 OE **PVA partly coated SNS fiber optic temperature sensor [13498-18]**
- 13498 OF **High-speed and large range measurement technology of microstructure surface morphology based on laser scanning lateral differential confocal [13498-20]**
- 13498 OG **Dual-wavelength squeezing interferometry with a novel double phase shift strategy: synthetic-wavelength interferometric fringe extraction by the conjugate complex function coupling [13498-23]**